IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Trung T. Doan

Title:

CHEMICAL DISPENSING SYSTEM FOR SEMICONDUCTOR WAFER PROCESSING

Docket No.:

303.928US5

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Examiner:

Sylvia MacArthur

Group Art Unit: 1763

MS AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

 \underline{X} Amendment and Response Under 37 CFR 1.116 (7 pgs.).

If not provided for in a separate paper filed herewith, Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

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(GENERAL)